

THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **MAIL STOP: RCE**
Norio KIMURA et al. : Docket No. 2001-0660A
Serial No. 09/864,208 : Group Art Unit 1763
Filed May 25, 2001 : Examiner Sylvia MacArthur

SUBSTRATE POLISHING APPARATUS AND: **Confirmation No. 1632**
SUBSTRATE POLISHING METHOD

PATENT OFFICE FEE TRANSMITTAL FORM

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Attached hereto is a check in the amount of \$880.00 to cover Patent Office fees relating to filing the following attached papers:

Request for Continued Examination (RCE) \$770.00

Petition for Extension of Time \$110.00

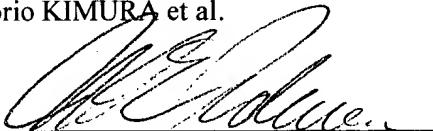
A duplicate copy of this paper is being submitted for use in the Accounting Division, Office of Finance.

The Commissioner is authorized to charge any deficiency or to credit any overpayment associated with this communication to Deposit Account No. 23-0975, with the EXCEPTION of deficiencies in fees for multiple dependent claims in new applications.

Respectfully submitted,

Norio KIMURA et al.

By



Nils E. Pedersen
Registration No. 33,145
Attorney for Applicants

NEP/krg
WENDEROTH, LIND & PONACK, L.L.P.
2033 K St., N.W., Suite 800
Washington, D.C. 20006-1021
Telephone (202) 721-8200
September 21, 2004

[Check No. 64226]
2001-0660A